

MAKING METHOD OF MICRO-LENS¹

Patent Number: KR9405965
Publication date: 1994-06-25
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Requested Patent: KR9405965
Application: KR19910017124 19910930
Priority Number(s): KR19910017124 19910930
IPC Classification: G02B5/20
EC Classification:
Equivalents:

Abstract

The method for increasing the incident light amount comprises the steps of: a) overlapping the micro lens onto the pixel, which width and length sides are different from each other, in direction of the short side; b) narrowing the short side of the black part rather than the long side to form the clear part; c) reflowing them thermally with a transparent photoresist; and d) forming the micro lens by depositing the photoresist deeply to have the curvature of the long and short axes to be the same.

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